

Notice of References Cited

Application/Control No.

10/578,805

Applicant(s)/Patent Under
Reexamination
HAMELINCK ET AL.

Examiner

YU CHEN

Art Unit

2815

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-7,268,081 B2	09-2007	Yang, Eui-Hyeok	438/694
*	C	US-5,867,302	02-1999	Fleming, James G.	359/291
*	D	US-6,384,952 B1	05-2002	Clark et al.	359/224.1
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	X	Bifano et al., "Surface Micromachined Deformable Mirrors", Conference on Emerging Technologies and Factory Automation (1996), Vol. 2, pp 393-399.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.